

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Daniel G. Stearns et al. Docket No. : CIL-10705B
Serial No. : 10/631,359 Art Unit: 1756
Filed : July 31, 2003 Examiner: S. Mohamedulla
For : EUV Lithography Reticles Fabricated
Without The Use Of A Patterned Absorber

**APPLICATION FOR
CHANGE IN CORRESPONDENCE ADDRESS**

Commissioner for Patents
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Dear Sir:

Please change the Correspondence Address for the above-identified
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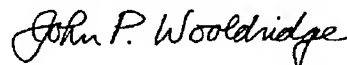
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If you have any questions, please contact the undersigned at 808-875-0012.

Respectfully submitted,



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Dated: September 2, 2004